

11/27/2009

ASMEX.433A

PATENT

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant : Matthew G. Goodman, et al.  
App. No : 10/775,522  
Filed : February 10, 2004  
For : TWO-STAGE LOAD FOR  
PROCESSING BOTH SIDES OF A  
WAFER  
  
Examiner : Sylvia MacArthur  
Art Unit : 1792

**RESPONSE TO OFFICE ACTION**

**Mail Stop AF**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Final Office Action dated September 15, 2009, Applicants have timely filed this Response. Applicants respectfully request the Examiner to grant allowance of this application in view of the following remarks:

**Listing of the Claims** begins on page 2 of this paper.

**Summary of Interview** begins on page 4 of this paper.

**Remarks** begin on page 5 of this paper.